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- (54) Title: FLUID FLOW COMPONENTS AND SYSTEM INCORPORATING SAME

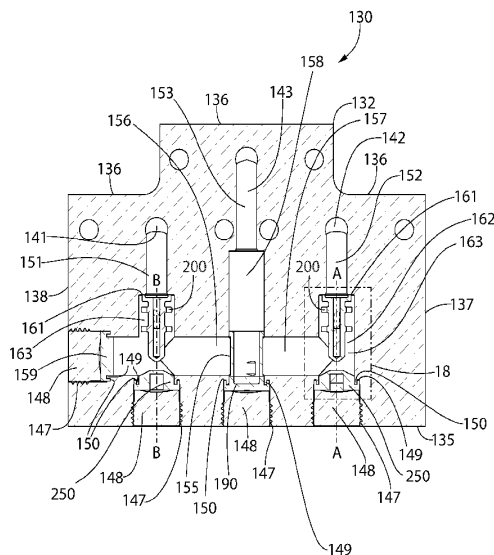


FIG. 5

(57) Abstract: Apparatuses for controlling fluid flow are important components for delivering process fluids for semiconductor fabrication. These apparatuses for controlling fluid flow frequently rely on fluid flow components which incorporate check valves to prevent reverse flow of fluids within the apparatuses for controlling fluid flow. The check valves make use of magnetic fields to enable biasing of a closure member against a seat without the need for mechanical biasing elements such as springs. These magnetic fields may be generated by one or more magnets, improving a wide range of operating parameters.

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